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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of

HATADA et al

Atty. Ref.: LSN-2635-197

Serial No. 10/743,409

TC/A.U.: 1753

Filed: December 23, 2003

Examiner:

For: GAS CONCENTRATION MEASURING APPARATUS

\* \* \* \* \*

January 22, 2007

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**INFORMATION DISCLOSURE STATEMENT**

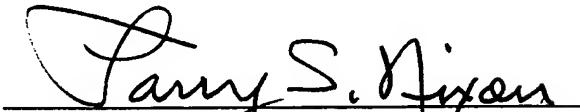
Attention is directed to the attached Japanese Office Action (and English translation) in a counterpart of this application and to a copy of each non-US patent document newly cited therein. A Form PTO/SB/08a is also attached.

Official consideration and citation of all identified documents is requested.

Respectfully submitted,

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INFORMATION DISCLOSURE CITATION	ATTY. DOCKET NO.	SERIAL NO.
	2635-197	10/743,409
	APPLICANT	
(Use several sheets if necessary)	HATADA et al	
	FILING DATE	GROUP
	December 23, 2003	1753

## **U.S. PATENT DOCUMENTS**

## FOREIGN PATENT DOCUMENTS

**OTHER DOCUMENTS (including Author, Title, Date, Pertinent pages, etc.)**

Japanese Office Action dated November 14, 2006 with English translation

*Examiner	Date Considered	
Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; drawin line through citation if not in conformance and not considered. Initial this form with next communication to application.		